

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Shimomura, et al.
Int'l Appl. No. : PCT/JP2004/015480
Int'l Filing Date : October 20, 2004
For : POLISHING PAD AND
SEMICONDUCTOR DEVICE
MANUFACTURING METHOD
Examiner : Unknown
Group Art Unit : Unknown

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Prior to calculation of the number of claims, please amend the present application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 6 of this paper.